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AF

Atty. Dkt. No. 025311-0105

UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Ichiro OKABE et al.

Title: METHOD OF FORMING A FINE PATTERN, AND METHOD OF
MANUFACTURING A SEMICONDUCTOR DEVICE, AND A
SEMICONDUCTOR DEVICE HAVING A FINE PATTERN

Appl. No.: 09/597,161

Filing Date: 06/20/2000

Examiner: Jose R. Diaz

Art Unit: 2815

AMENDMENT AND REPLY UNDER 37 CFR 1.116

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Final Office Action dated May 18, 2005,
concerning the above-referenced patent application.

Amendments to the Claims are reflected in the listing of claims which begins on
page 2 of this document.

Remarks/Arguments begin on page 4 of this document.

Please amend the application as follows: